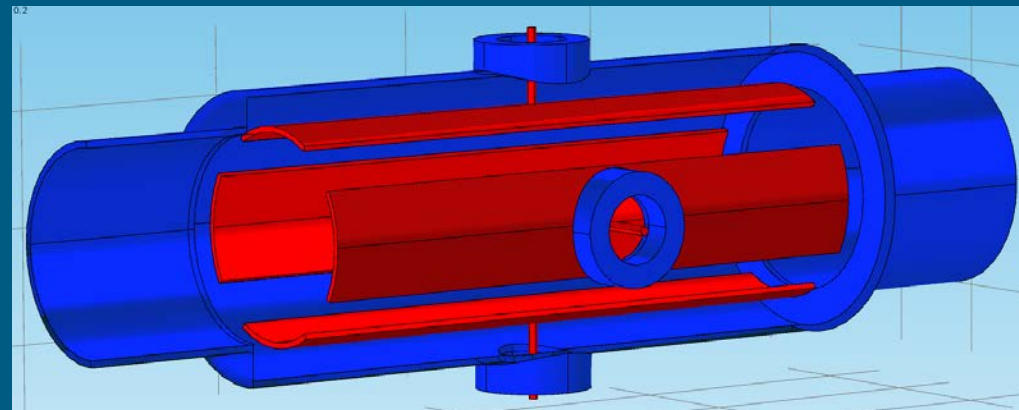


# Characterization of BPM pickup designs for the HESR @ FAIR using simulations and numerical calculations

Arbeitskreis Beschleunigerphysik 12.2:  
Beam Diagnostics

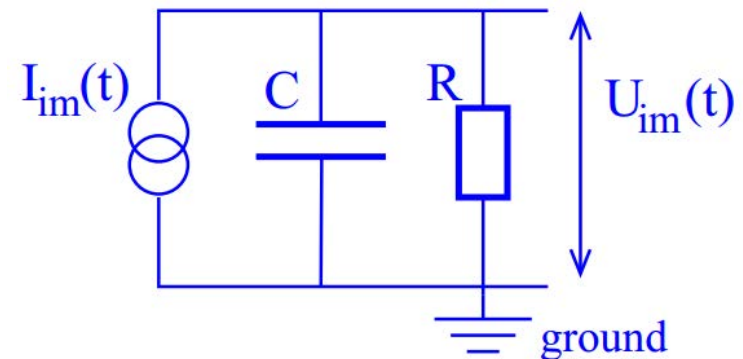
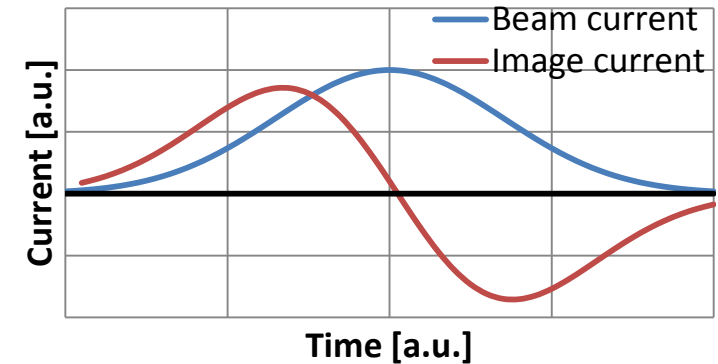
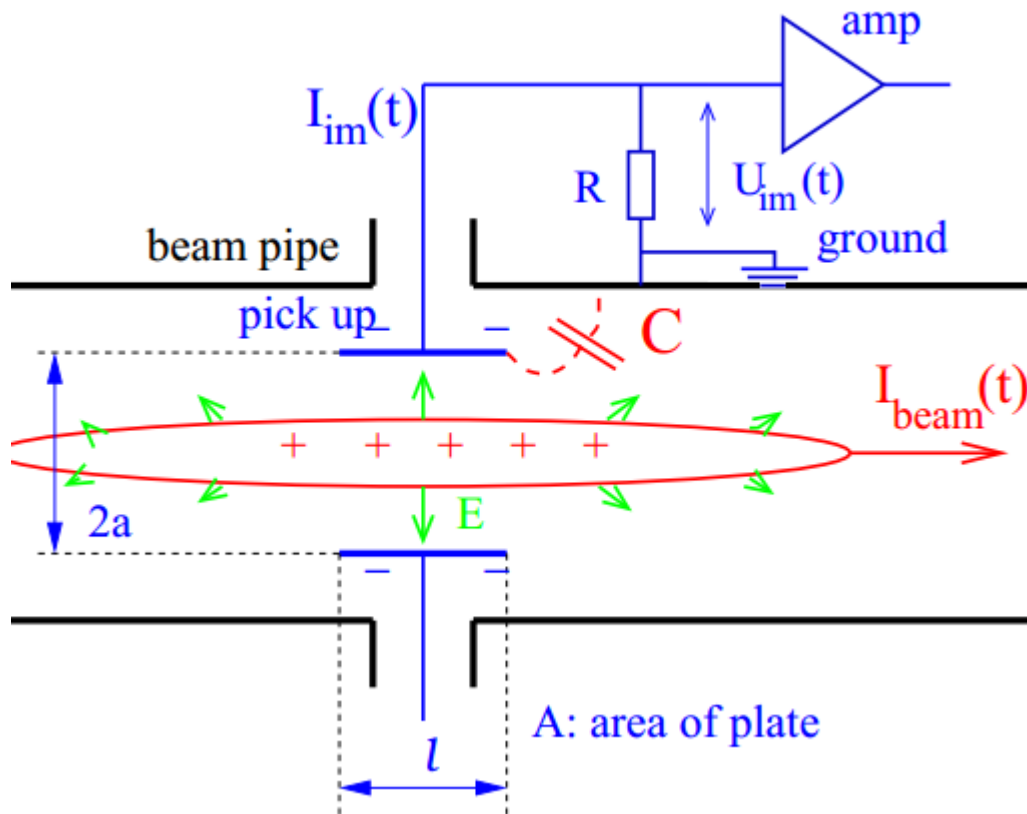


IKP-4, Forschungszentrum Jülich  
A.Halama, March 17, 2016 | 14:15

# Contents

- Quick capacitive BPM basics
- A look at both designs
- Position dependent properties
  - Signal yield
  - Sensitivity
- Unwanted inherent features / characteristics

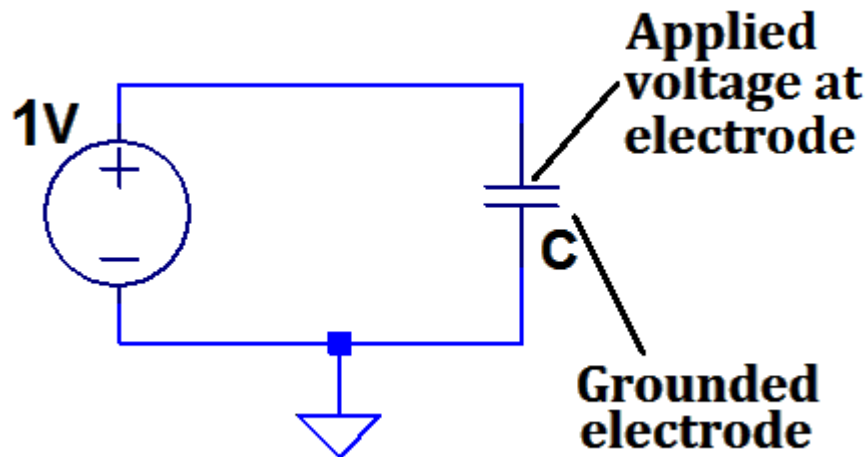
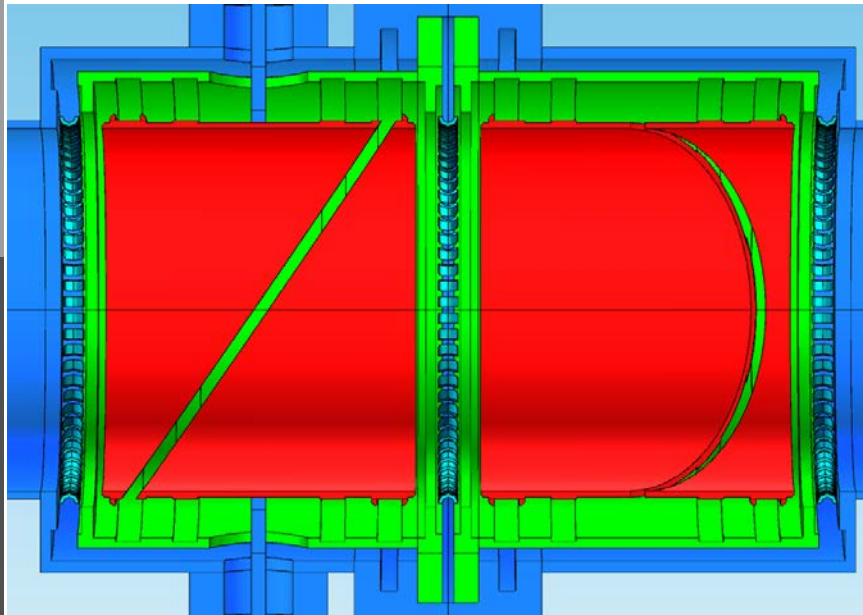
# Image current flowing onto and from the electrodes → differentiated signal shape



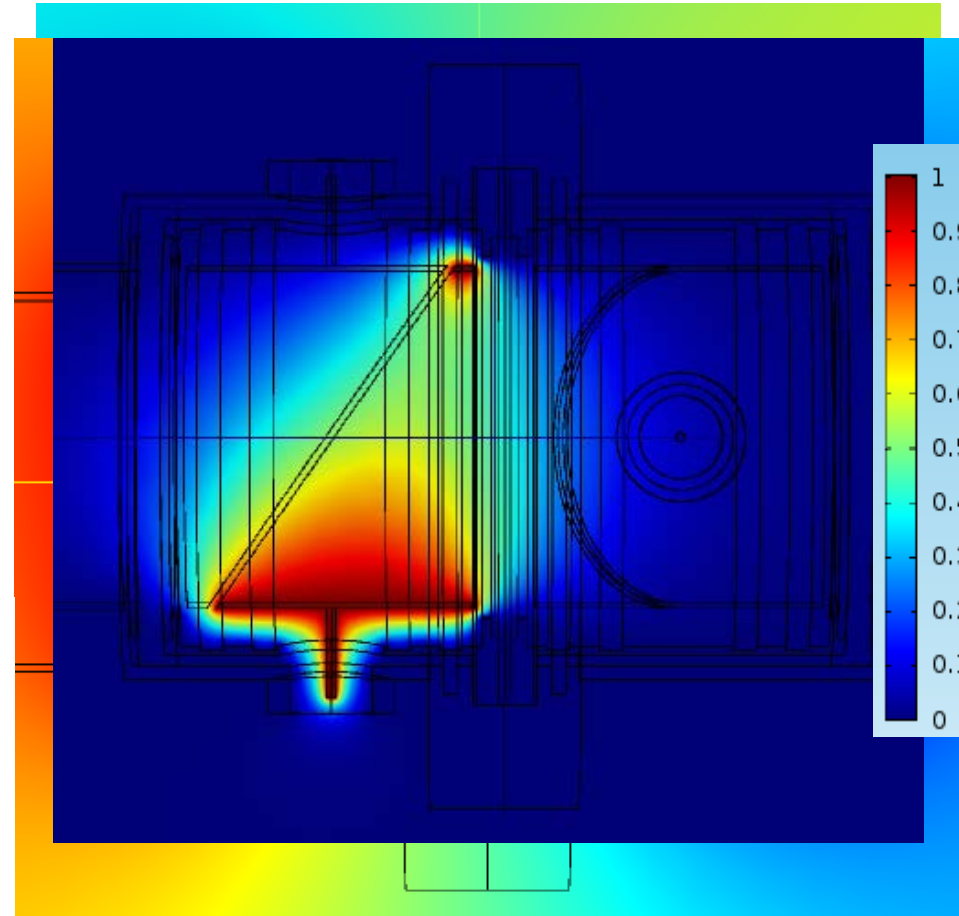
$$I_{\text{im}}(t) = -\frac{N e t L_{\text{BPM}}}{2\sqrt{2\pi} \sigma^3 \beta c} e^{-\frac{1}{2}\left(\frac{t}{\sigma}\right)^2}$$

Sources: „Beam Position Monitors“ by P. Forck, P. Kowina, D. Liakin, GSI

# Capacitance determination using COMSOL

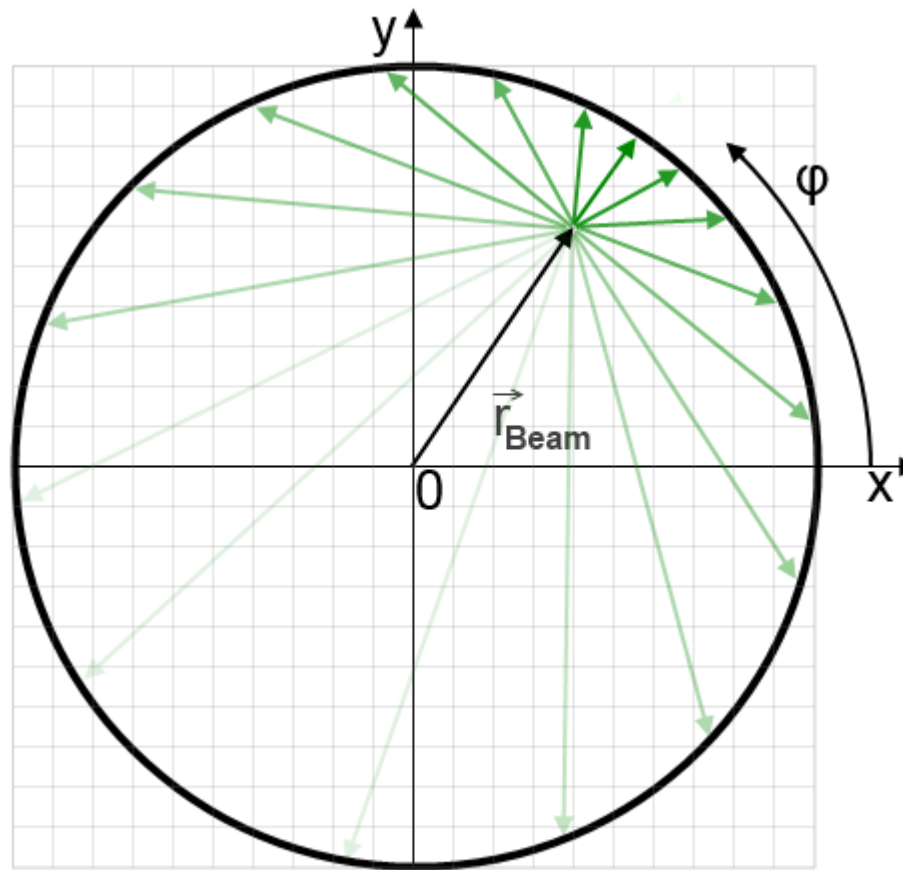


Electrical potential, [ V ]



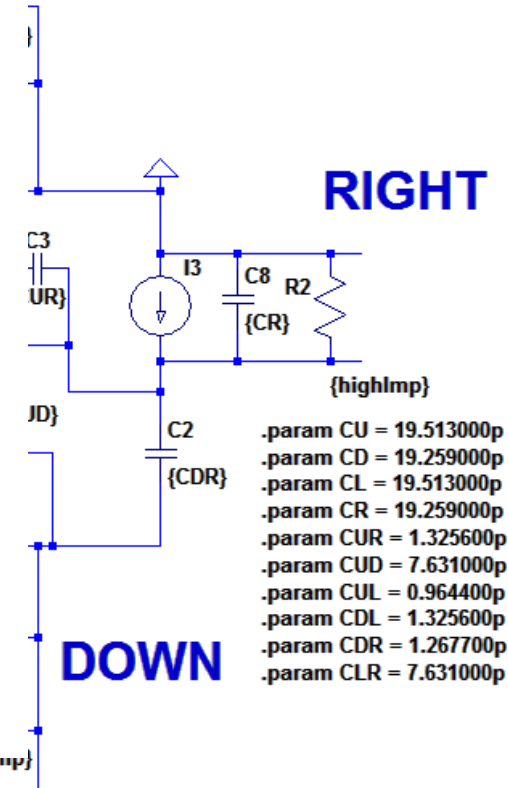
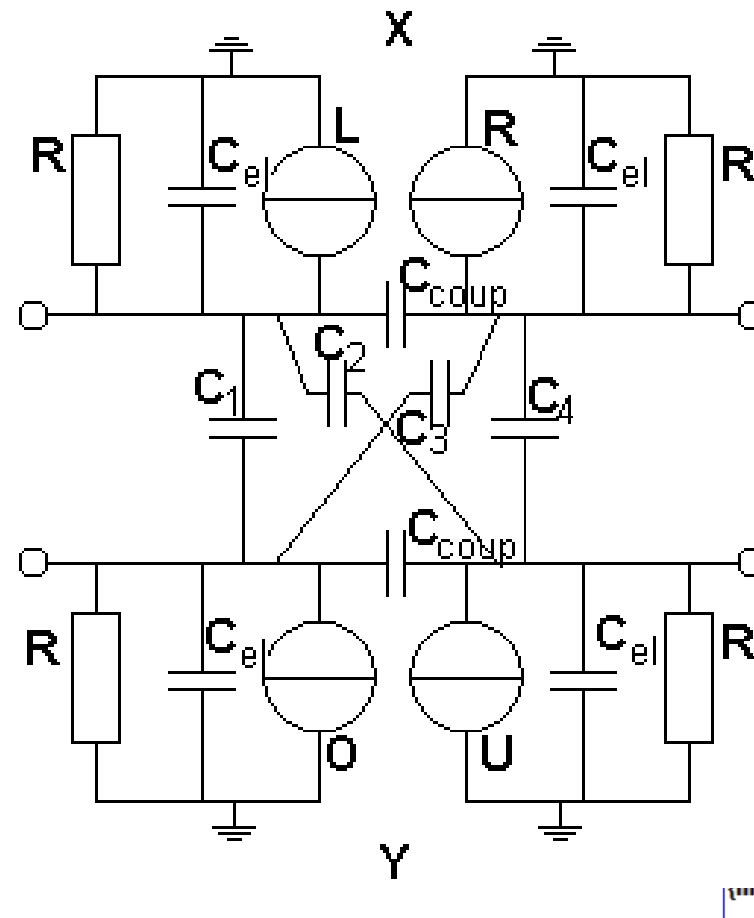
Electric field simulation leads to capacitances as a byproduct

# Image current scaling factors given by position dependent influence

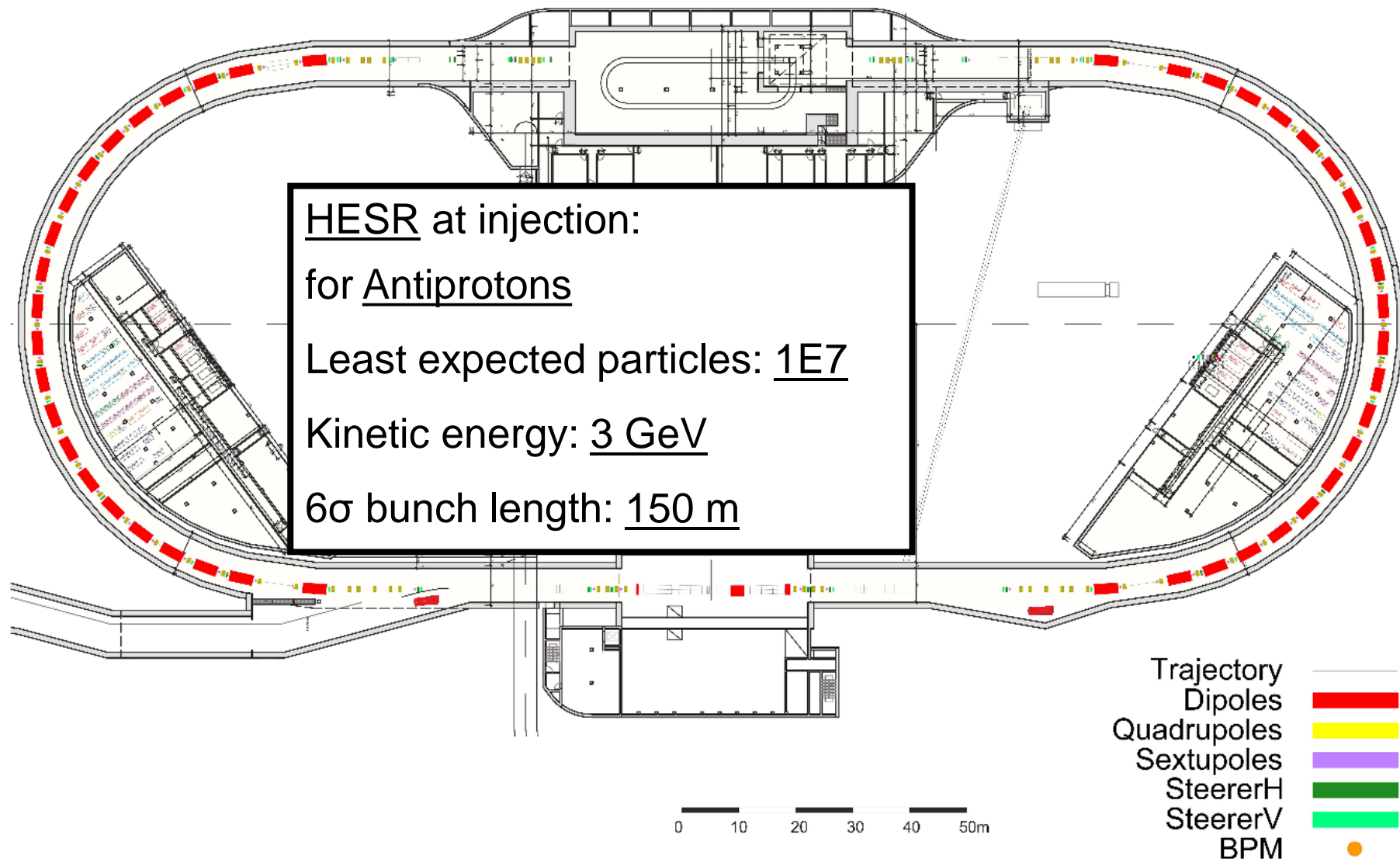


$$\text{Influence} \propto \int_{\varphi_0}^{\varphi_1} \frac{l(\varphi)}{(\cos(\varphi) r_{\text{BPM}} - X_{\text{beam}})^2 + (\sin(\varphi) r_{\text{BPM}} - Y_{\text{beam}})^2} d\varphi$$

# Equivalent circuit for 4 electrodes



# Considered Input Parameters

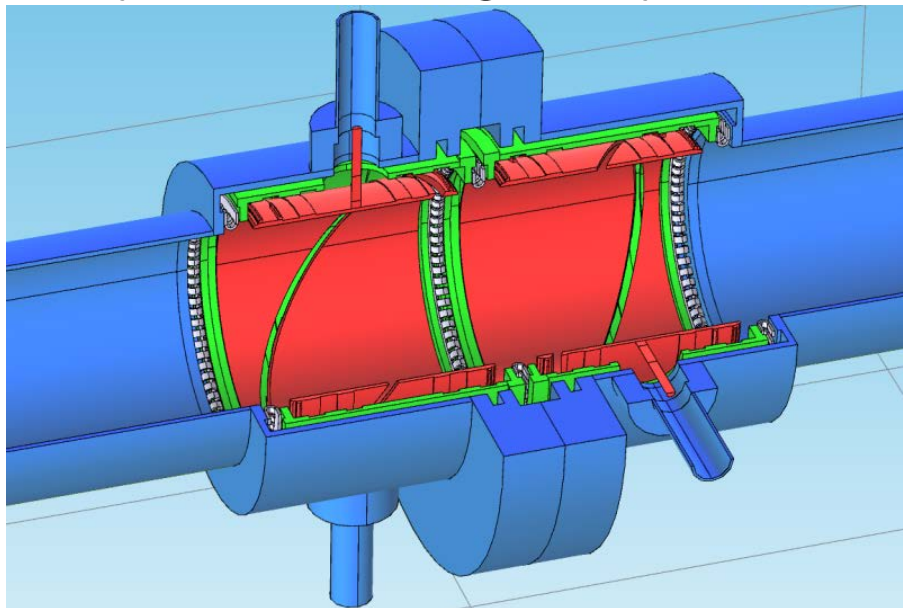


Sources: IKP database / [http://www.fz-juelich.de/ikp/DE/Forschung/Beschleuniger/HESRfuerEinsteiger\\_node.html](http://www.fz-juelich.de/ikp/DE/Forschung/Beschleuniger/HESRfuerEinsteiger_node.html)



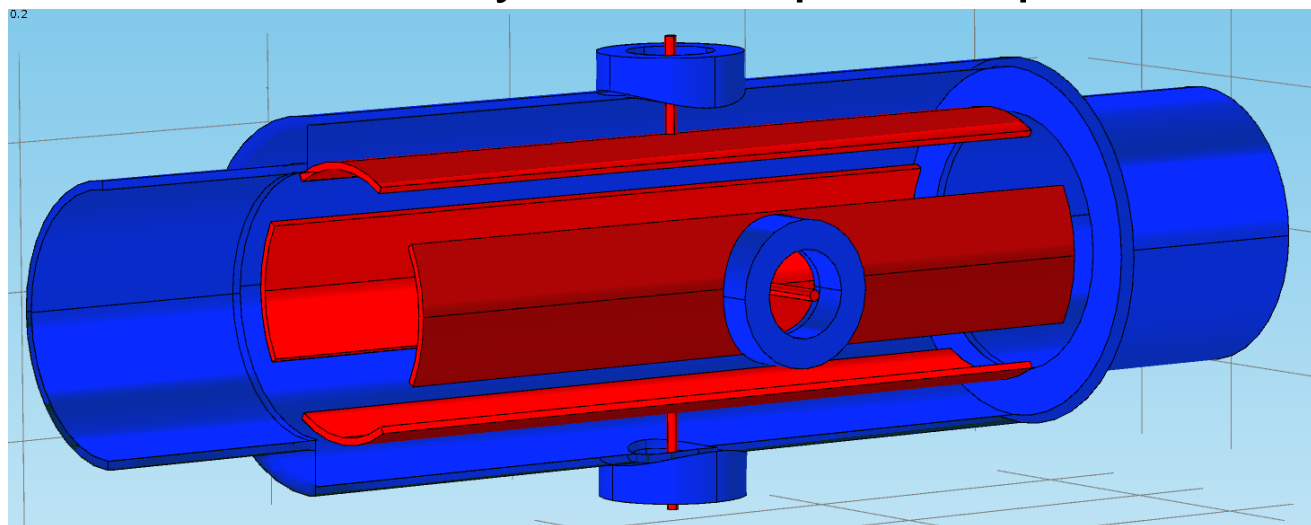
# Both BPM Designs

## Cylindrical diagonally cut



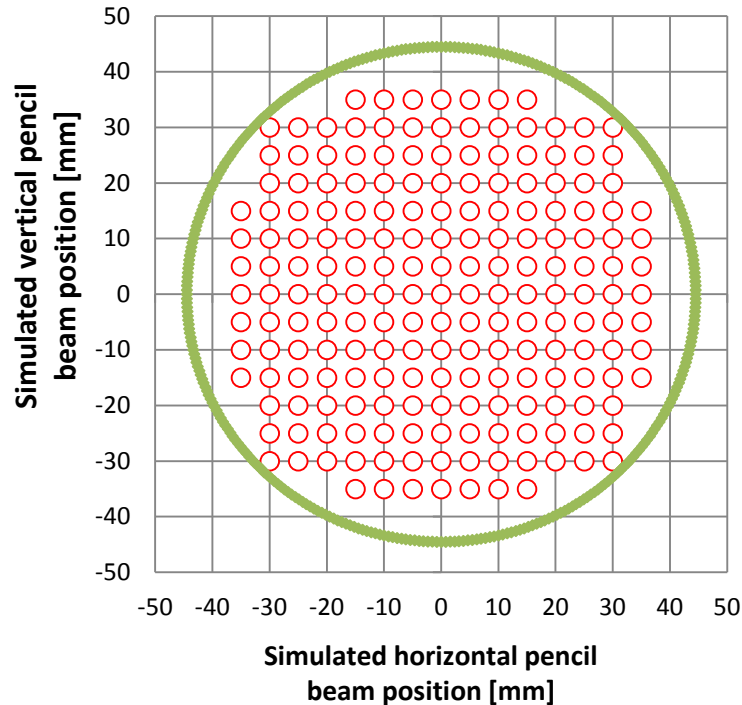
- Antiproton turn-by-turn measurement at injection is unlikely with current design.
- Higher signal level, S/N-ratio and sensitivity expected with less coupling expected.

## Symmetric quad strips





# Simulating each beam position



After capacitance determination;

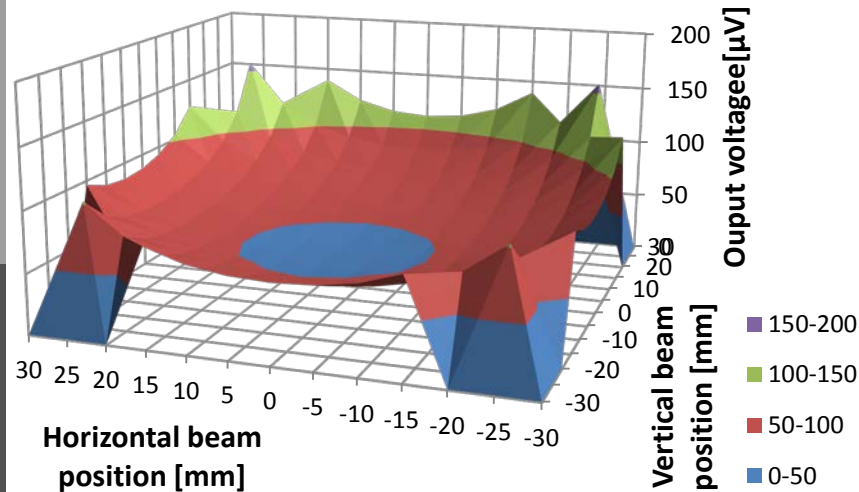
- Retrieve scaling factors for each beam position for all electrodes
- Run through equivalent circuit
- Analyse output voltages

○ actual beam position

◆ Electrodes

# Signal level distributions

## Cylindrical diagonally cut



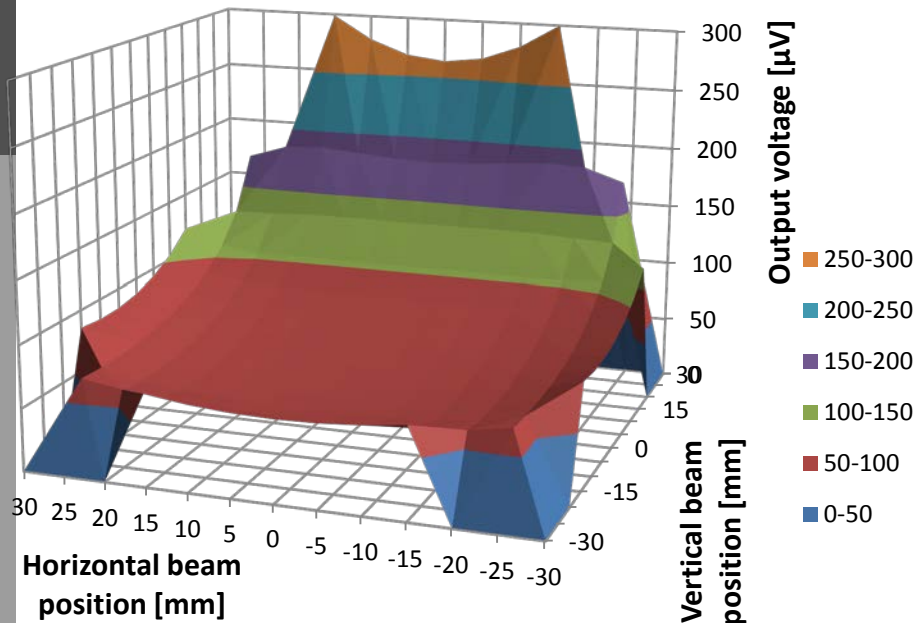
Peak output voltage distribution at a single electrode at high impedance, R

Peak output voltages at center:

Cyl. diag cut:  $\sim 48\mu\text{V}$

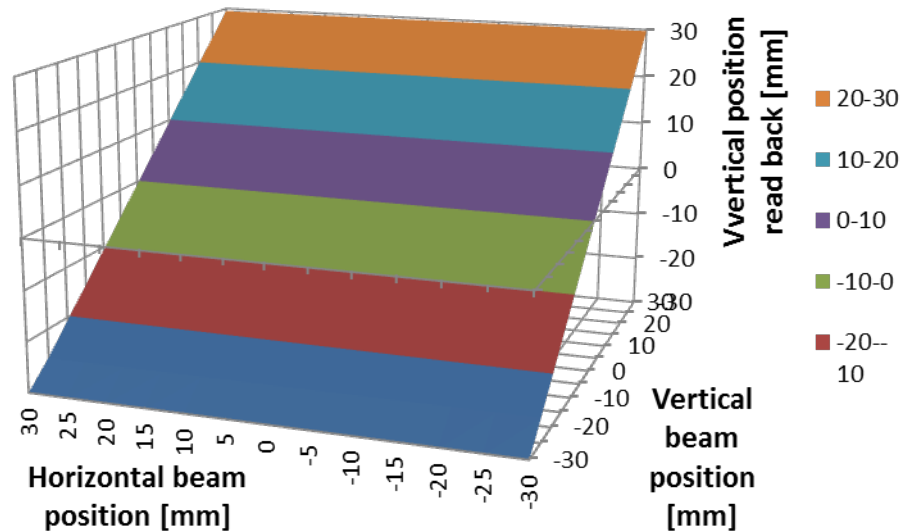
Symm. quad:  $\sim 63\mu\text{V}$

## Symmetric quad strips



Strip BPM distribution is steeper and suggests higher sensitivity

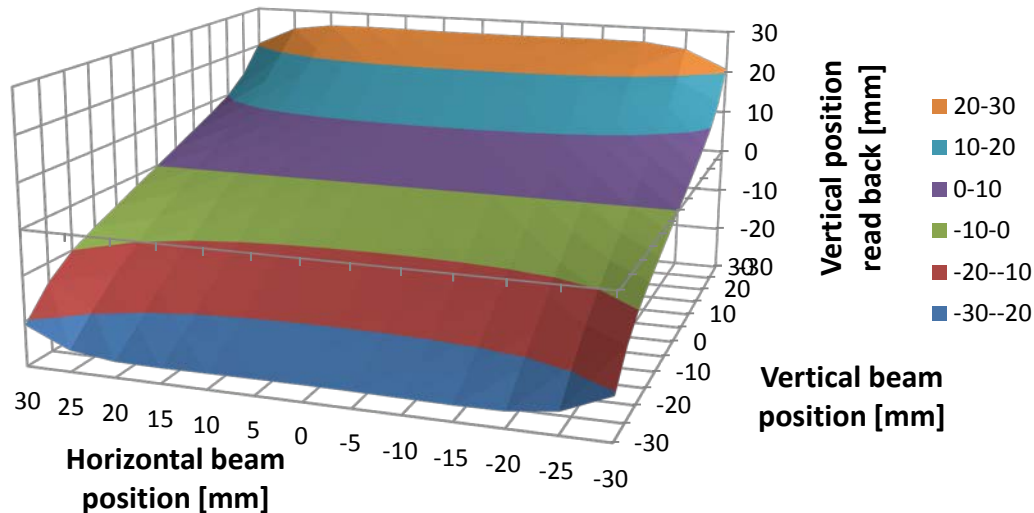
Cylindrical diagonally cut



$$S_y(x, y) = \frac{d}{dy} \frac{\Delta_y(x, y)}{\Sigma_y(x, y)} = \frac{d}{dy} \frac{U_U - U_D}{U_U + U_D}$$

$$y = \frac{1}{S_y} \frac{\Delta_y}{\Sigma_y} \quad x = \frac{1}{S_x} \frac{\Delta_x}{\Sigma_x}$$

Symmetric quad strips

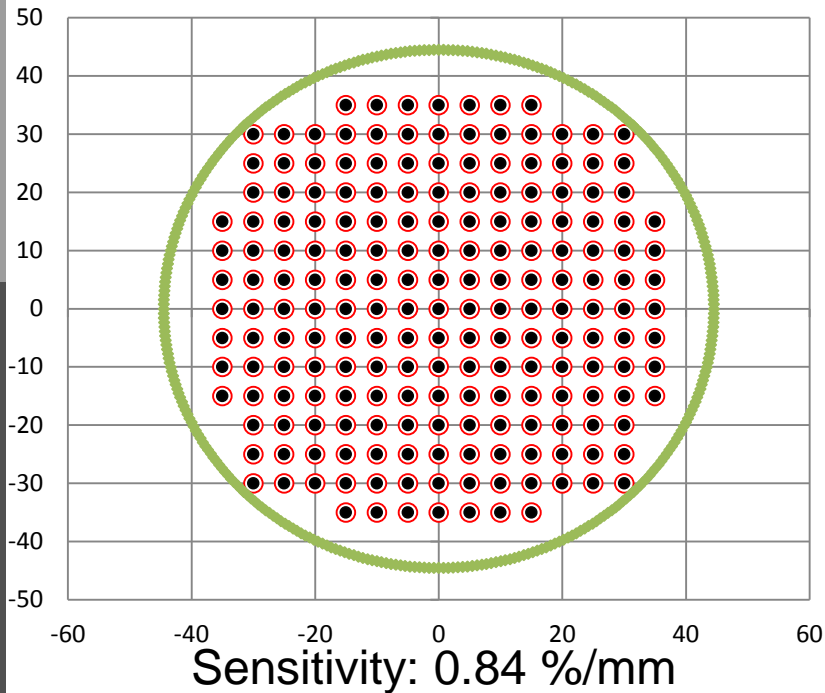


Average sensitivity:  
 $S_y = 0.84 \text{ \%/mm}$

Center sensitivity:  
 $S_y = 2.28 \text{ \%/mm}$

# Position projection

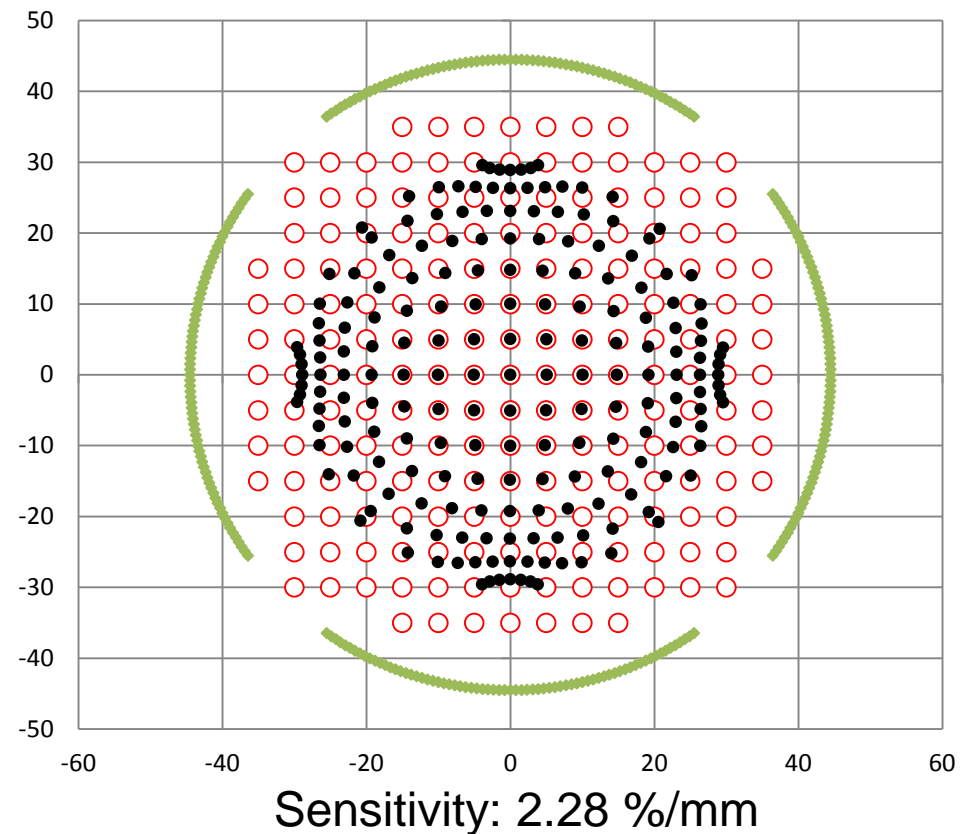
Cylindrical diagonally cut



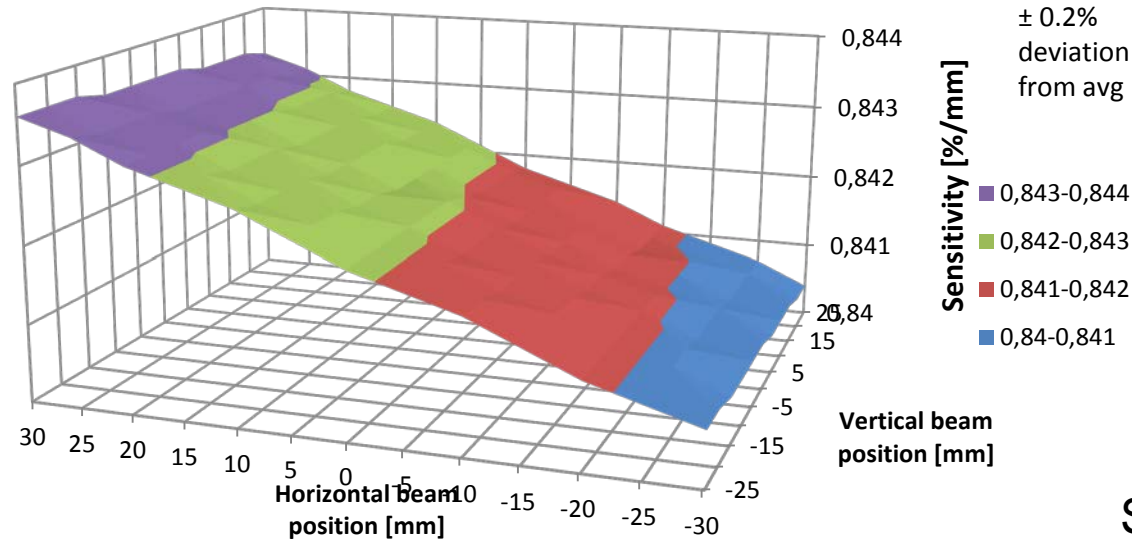
- actual beam position
- projected beam position
- ◆ Electrodes

$$y = \frac{1}{S_y} \frac{\Delta_y}{\Sigma_y}$$

Symmetric quad strips

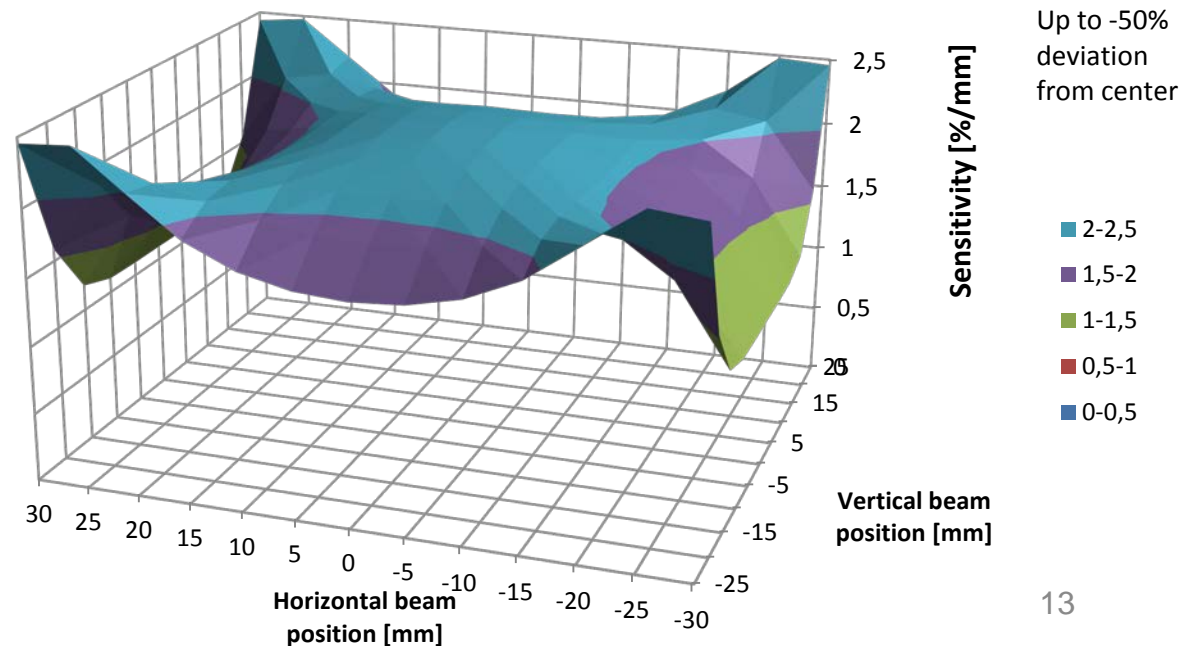


## Cylindrical diagonally cut

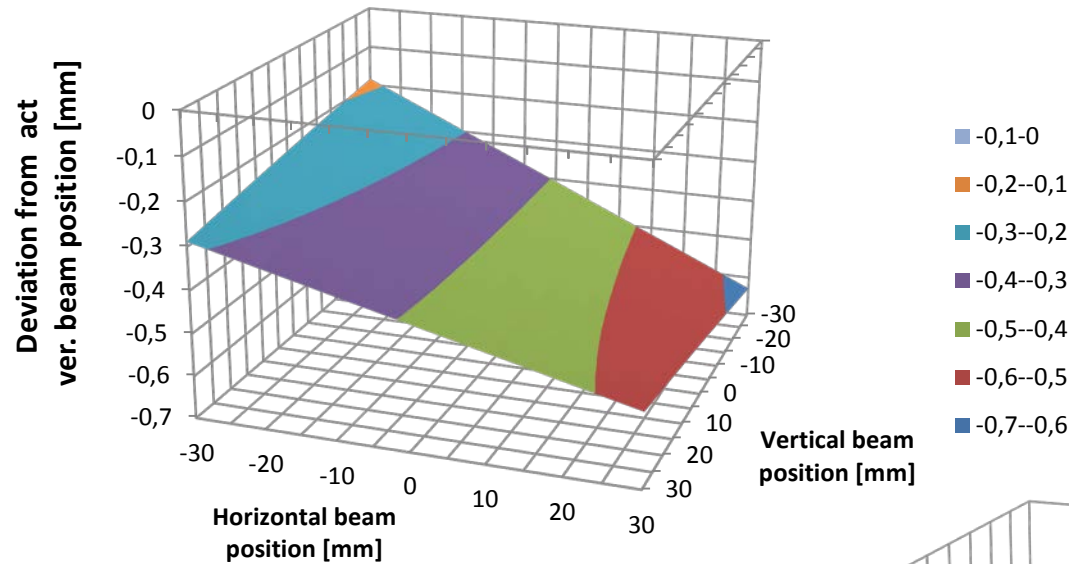


$$S_y(x, y) = \frac{d}{dx} \frac{\Delta_y(x, y)}{\Sigma_y(x, y)}$$

## Symmetric quad strips

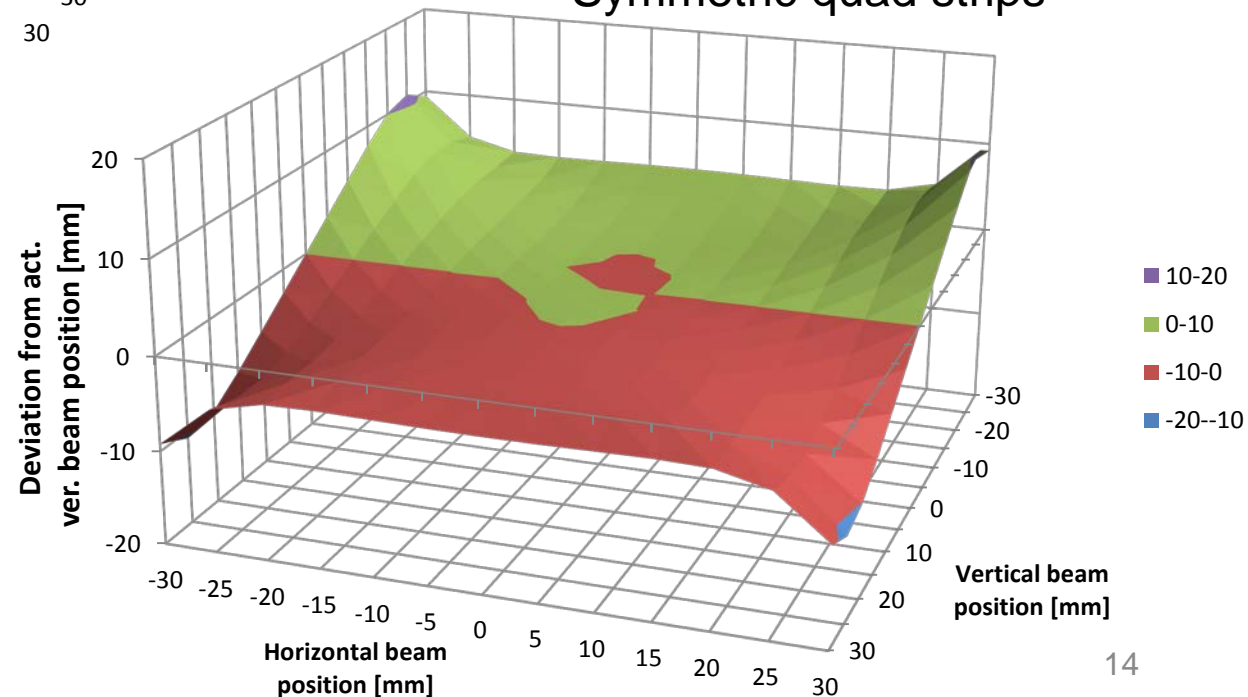


## Cylindrical diagonally cut



- Offset
- Asymmetric coupling

## Symmetric quad strips

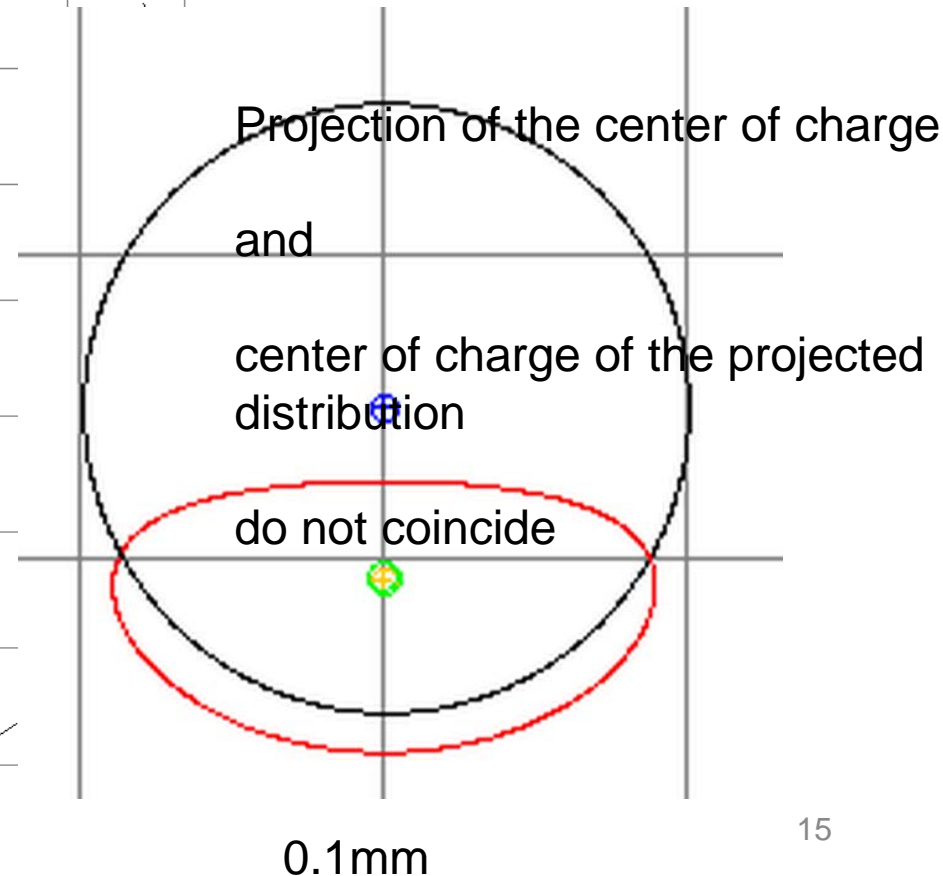
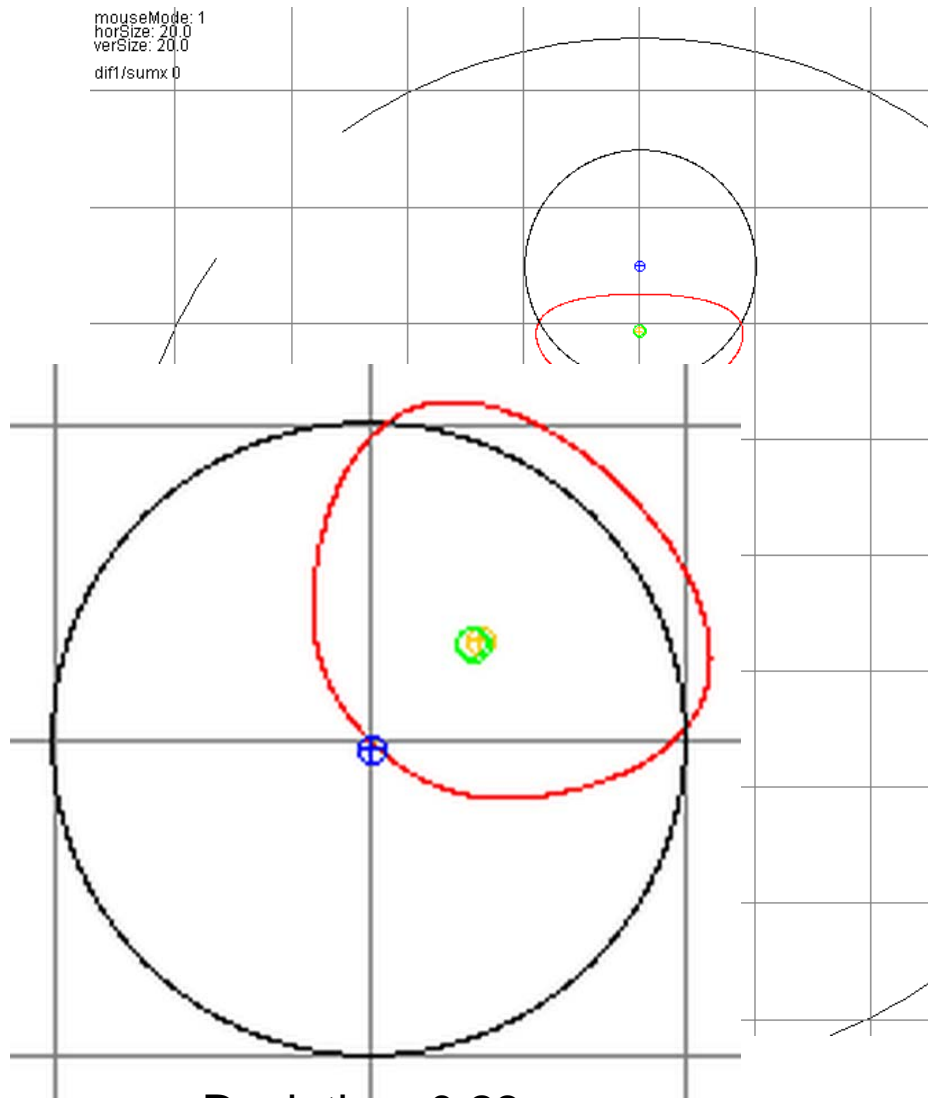


# Inherent unwanted features

## Symmetric quad strips

- Offset
- Asymmetric coupling
- False projection of charge distribution

mouseMode: 1  
horSize: 20.0  
verSize: 20.0  
dif1/sumx: 0





# Thank you

## References

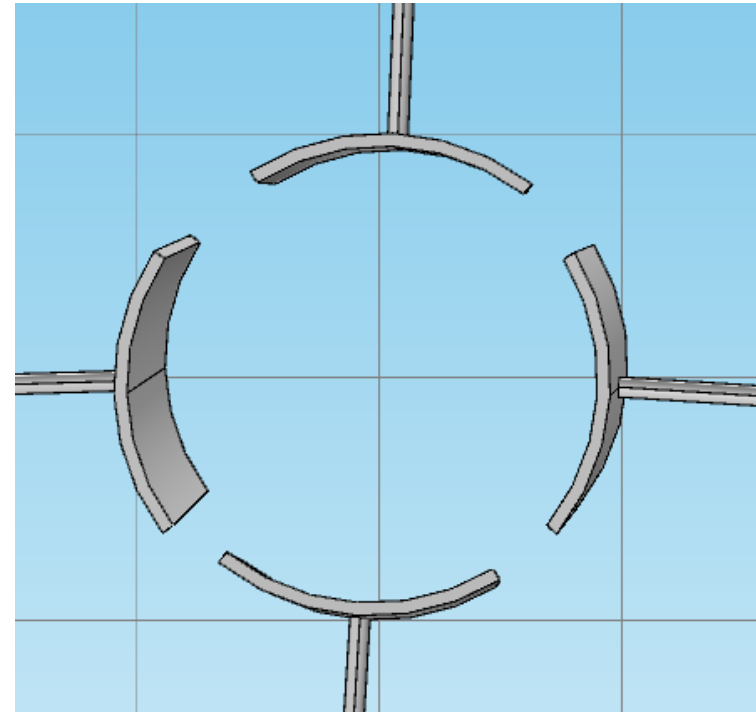
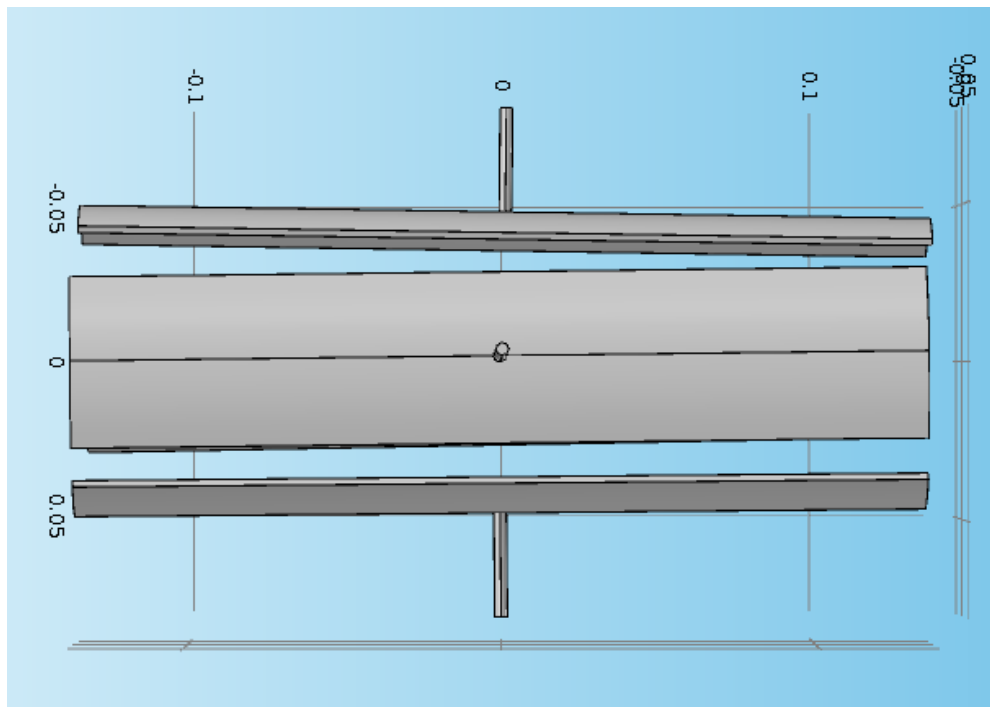
- C. Böhme - Annual Report 2014: „Beam Position Monitors for the HESR “ & AR2015: „Status of the HESR BPM “, FZJ
- P. Forck, P. Kowina, D. Liakin: „Beam Position Monitors“, GSI
- R.E. Shafer: „Beam Position Monitoring“

Randomly skewed electrodes were

yaw:  $1.45^\circ \approx 25 \text{ mrad}$ ; pitch:  $1.45^\circ \approx 25 \text{ mrad}$ ; roll:  $4.00^\circ \approx 70 \text{ mrad}$

each 1-dim. offset : 2 mm

At least 20% of this error +80 % random



$$\alpha_{\text{rms}} = 0.95^\circ; \quad \beta_{\text{rms}} = 0.94^\circ; \quad \gamma_{\text{rms}} = 2.6^\circ; \quad x, y, z_{\text{rms}} = 1.28 \text{ mm}$$

$$(\Delta C / C)_{\text{rms}} = 1.27 \% \quad (\text{Capacitances})$$

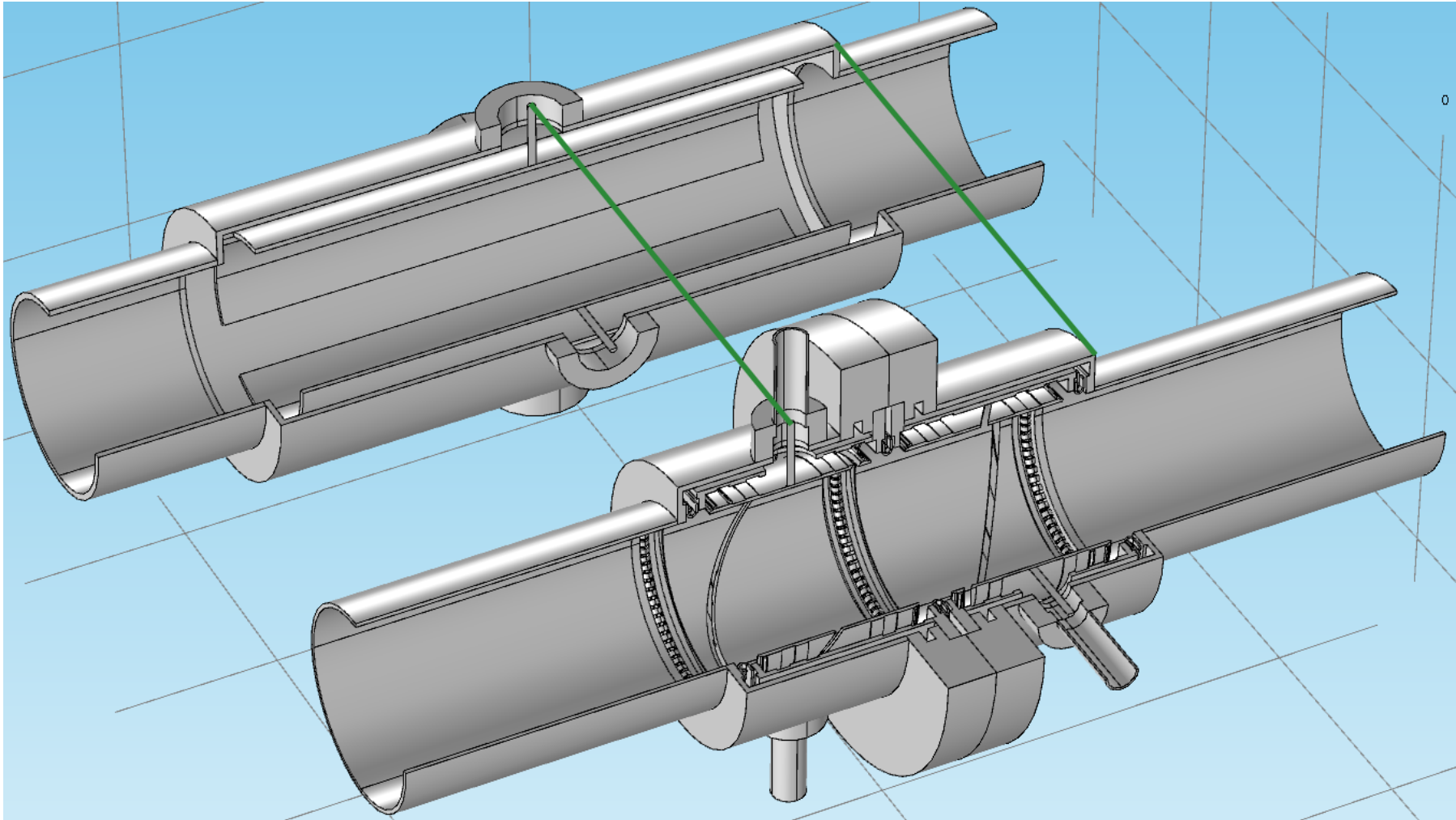
$$(\Delta F_{\text{curr}} / F_{\text{curr}})_{\text{rms}} = 1.15 \% \quad (\text{Scaling factors})$$

$$(\Delta X / X)_{\text{rms}} = 34,7 \% \quad (\text{Beam Position})$$

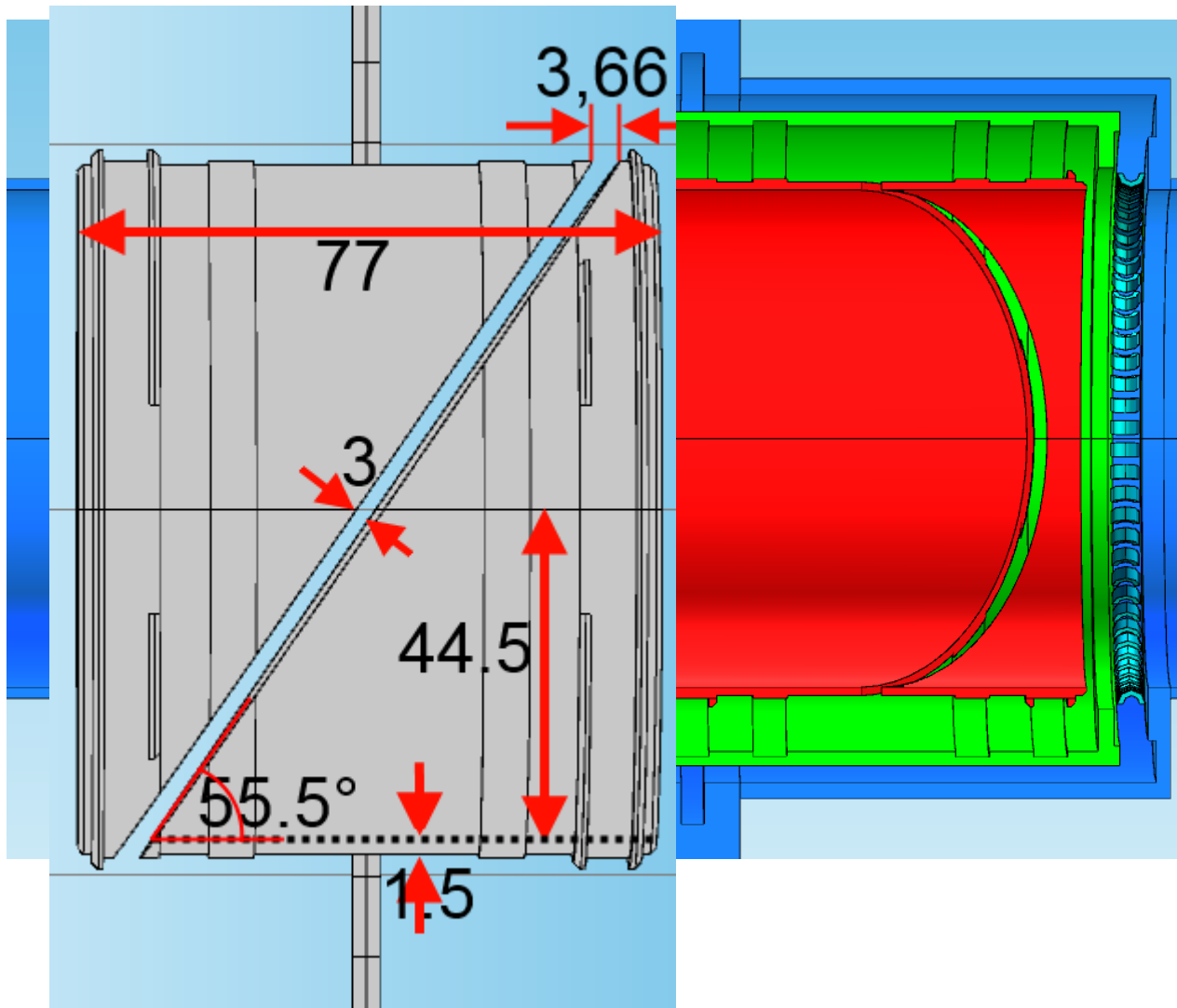
$$(\Delta S_x / S_x)_{\text{rms}} = 13,8 \% \quad (\text{Sensitivity})$$

$$X_{\text{offset rms}} \approx 2 \text{ mm} \quad (\text{Electrical Offset})$$

# Considering Length of Electrode

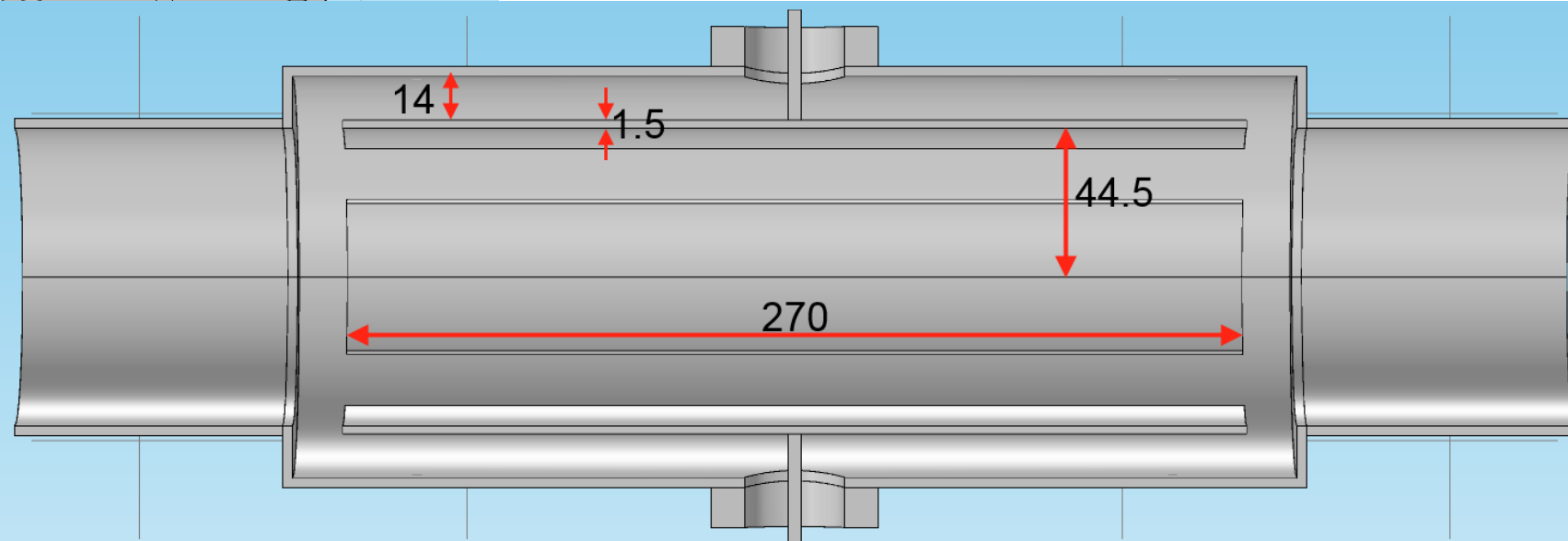
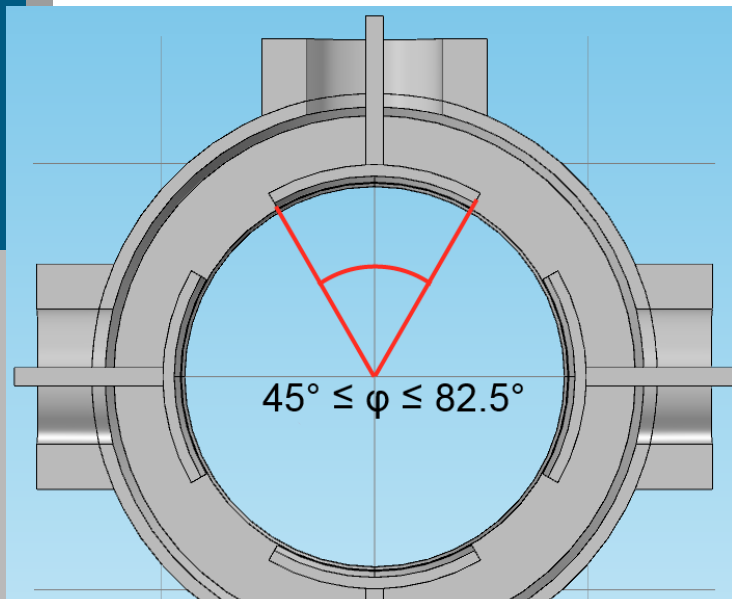


# Cylindrical Diagonal Cut BPM PU

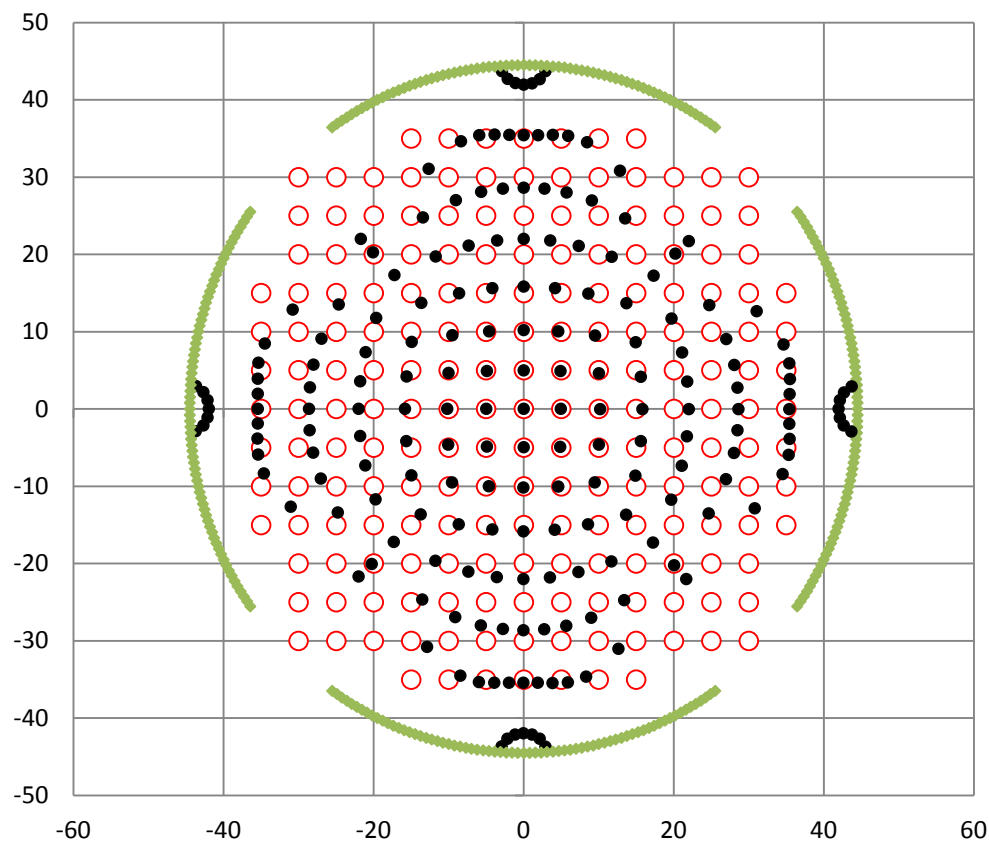


# New BPM PU Design Concept

Greatest length of PU (270 mm) while being symmetric



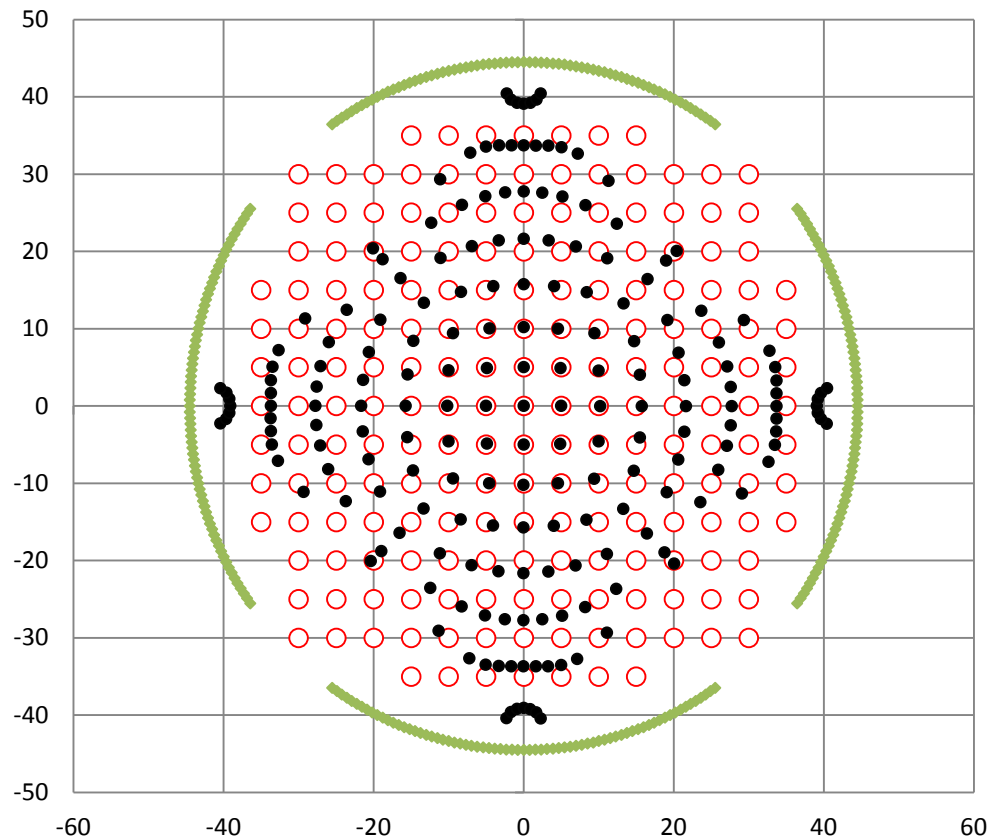
$$\ln\left(\frac{U_1+U_2}{U_3+U_4}\right) \rightarrow 3.32 \text{ \%/mm}$$



- actual beam position
- projected beam position
- ◆ Electrodes

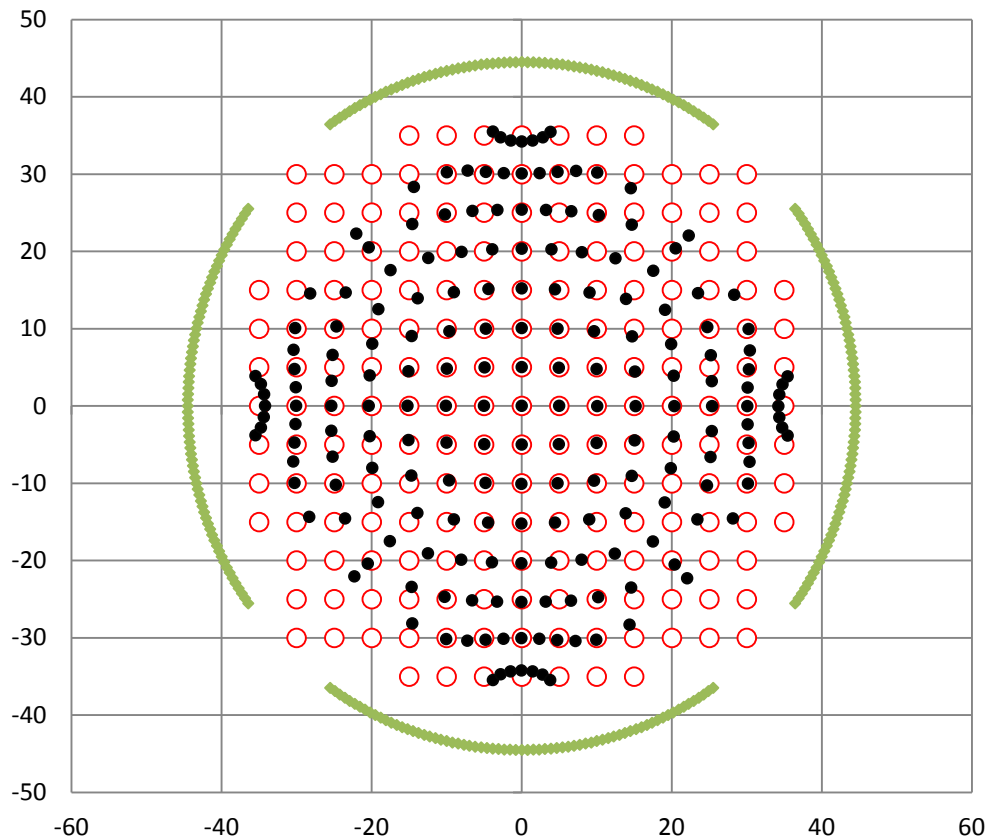


$$\frac{\Delta y}{\Sigma_{xy}} \rightarrow 1,17 \text{ \%/mm}$$



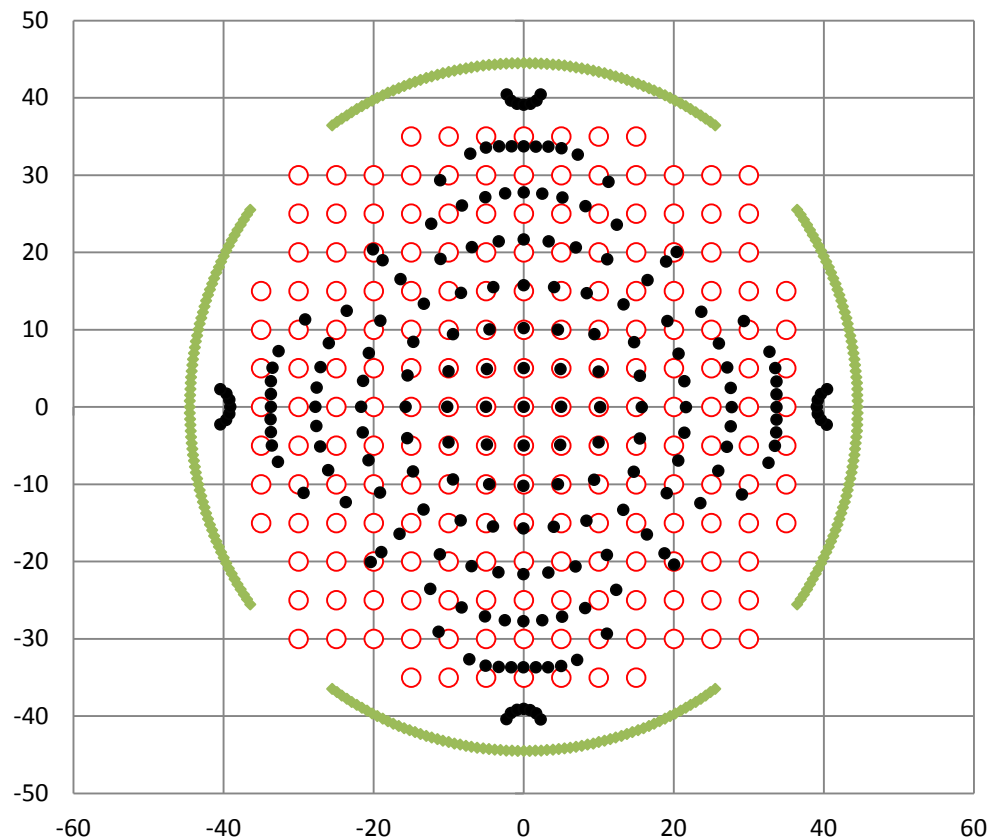
- actual beam position
- projected beam position
- ◆ Electrodes

$$\ln\left(\frac{U_p}{U_{Down}}\right) \rightarrow 4.63 \text{ \%/mm}$$



- actual beam position
- projected beam position
- ◆ Electrodes

$$\frac{U1+U2-U3-U4}{\Sigma_{xy}} \rightarrow 1,65 \text{ \%/mm}$$



- actual beam position
- projected beam position
- ◆ Electrodes